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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant(s): Vyvoda, et al.                           |                      |
| Application No.: 09/776009                             | Group Art Unit: 2814 |
| Filed: 02/02/2001                                      | Examiner: Anh D. Mai |
| Title: Wafer Surface that Facilitates Particle Removal |                      |
| Attorney Docket No.: MA-027                            |                      |
| Assistant Commissioner for Patents                     | July 3, 2003         |
| Washington, D.C. 20231                                 |                      |

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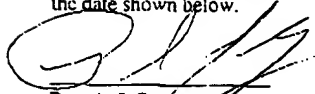
JUL 03 2003

TECHNOLOGY CENTER 2800

**OFFICE ACTION RESPONSE AFTER FINAL**

Please enter the following remarks in response to the Office Action of May 7, 2003, and is filed within two months of mailing of the Office Action. In this response no claims are amended, cancelled or withdrawn, and no new claims are proposed. As there are no changes to the claims, no listing of pending claims is included.

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Pamela J. Squyres

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App. No. 09/776009

1

Matrix Semiconductor, Inc.  
3230 Scott Boulevard  
Santa Clara, California 95054  
Telephone 408.969.4848  
Facsimile 408.969.4849

Date: July 3, 2003

Time: \_\_\_\_\_  
(Santa Clara, California)

TO: Commissioner for Patents  
Attn: Anh D. Mai  
Patent Examining Corps  
Facsimile Center  
Washington, D.C. 20231

FROM: Pamela J. Squyres

OUR REF: MA-027

TELEPHONE: 408-869-2921

**FAX NUMBER 703-308-7722**

\* Please deliver to Examiner Anh D. Mai in Art Unit 2814. \*

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Document(s) Transmitted: Fax Cover Sheet (1 pg)  
Transmittal Form (1pg)  
Response (9pgs)  
Applicant Initiated Interview Request Form (1 pg)

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Re:

Patent Application of: Michael A. Vyvoda et al.

Examiner: Anh D. Mai

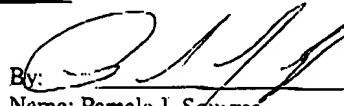
Serial No.: 09/776009

Group Art Unit: 2814

Filed: February 2, 2001

Docket No.: MA-027

Title: Wafer Surface that Facilitates Particle Removal

By:   
Name: Pamela J. Squyres  
Reg. No.: 52,246

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